

In the Claims

1. (Currently amended) Epitaxy equipment comprising:

an epitaxy chamber under vacuum containing a substrate support and at least one cell under vacuum for evaporation of epitaxy material closed by a diaphragm having at least one opening and communicating with the epitaxy chamber by a connecting flange, and

a mobile plate positioned opposite the diaphragm such that the distance of the plate from an exterior surface of the diaphragm is variable and has a cross section corresponding to a cross section of the diaphragm and a molecular beam is formed at ~~the~~ a level of a zone surrounding the plate.

2. (Original) The epitaxy equipment according to claim 1, wherein the plate is disc-shaped.

3. (Original) The epitaxy equipment according to claim 1, wherein the plate is mobile in a direction perpendicular to the diaphragm.

4. (Original) The epitaxy equipment according to claim 2, wherein the distance is 10 millimeters.

5. (Currently amended) ~~The epitaxy~~ Epitaxy equipment according to claim 1 comprising:
an epitaxy chamber under vacuum containing a substrate support and at least one cell under vacuum for evaporation of epitaxy material closed by a diaphragm having at least one opening and communicating with the epitaxy chamber by a connecting flange,

an wherein the plate is angularly mobile plate positioned opposite the diaphragm such that the plate and forms a dihedron variable with a plane of the diaphragm, the distance of a center of the plate from an exterior surface of the diaphragm being variable,

the plate having a cross section corresponding to a cross section of the diaphragm, and
a molecular beam being formed at a level of a zone surrounding the plate.

6. (Original) The epitaxy equipment according to claim 1, wherein the plate is made of metal or a dielectric material.

7. (Currently amended) The epitaxy equipment according to claim 1, wherein the plate is actuated by a ~~connecting organ~~ control rod traversing a wall of the epitaxy chamber via an airtight passage.

8. (Original) The epitaxy equipment according to claim 1, wherein the diaphragm has perforations.

9. (Original) The epitaxy equipment according to claim 1, wherein the diaphragm has an annular opening.